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Attorney Docket No. 29195-8117

**Proposed Claim Amendments
For Discussion Purpose Only**

PATENT**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

IN RE APPLICATION OF: THOMAS L. RITZDORF

APPLICATION No.: 09/612,176

FILED: July 8, 2000

FOR: APPARATUS AND METHOD FOR PROCESSING A
MICROELECTRONIC WORKPIECE USING
METROLOGY

EXAMINER: Zandra V. Smith

ART UNIT: 2877

CONF. No: 7779

Proposed Claim Amendment

1. (Amended) A processing apparatus for processing a microelectronic workpiece, comprising:

an in-line metrology unit having a space for receiving a microelectronic workpiece for measuring a condition of a first layer on said microelectronic workpiece and generating a condition signal;

a control, signal-connected to said metrology unit;

a process unit providing a space to receive said microelectronic workpiece and performing a material application process that is controlled by said control; and

wherein said condition signal from said metrology unit to said control influences said process; and

a transport unit positioned to receive the microelectronic workpiece from at least one of the process unit and the in-line metrology unit and move the microelectronic workpiece to the other of the process unit and the in-line metrology unit.

Attorney Docket No. 29195-8117

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REMARKS

The foregoing claim is submitted for discussion purposes only in an upcoming telephone interview scheduled for Thursday, September 26, 2002.

Respectfully submitted,

Perkins Coie LLP

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